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(21)Application number : 2000-247496 (71)Applicant : CHUGAI RO CO LTD

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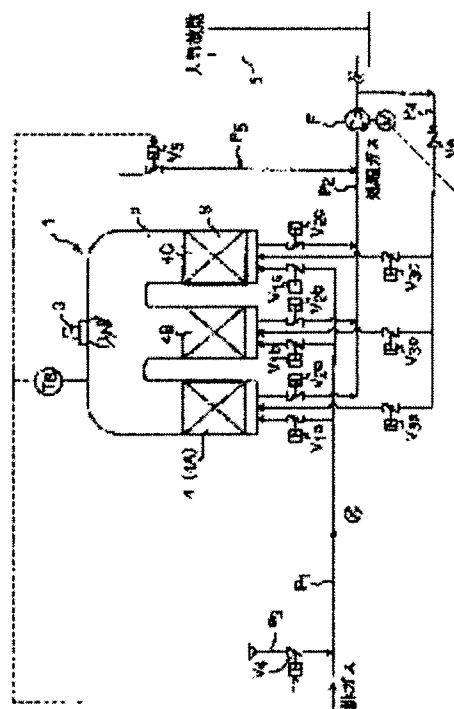
(54) METHOD FOR TREATING EXHAUST GAS BY HEAT-STORAGE EXHAUST-GAS TREATING EQUIPMENT

(57)Abstract:

PROBLEM TO BE SOLVED: To provide a method for preventing a heat-storage body from being clogged with silica and/or crystallized silicon in a treatment of an organic silicon and an exhaust gas containing a hazardous component by heat-storage exhaust-gas treating equipment.

SOLUTION: This exhaust-gas treatment equipment is provided with at least two heat-storage chambers 4 having heat-storage bodies S. One end of the each chamber is allowed to communicate with a combustion chamber 2 provided with a heating means 3, and the other end thereof is allowed to communicate with an exhaust gas-supply duct P1 and a treated-gas exhaust duct P2 respectively through open/close valve V1a-V3c.

The supply of exhaust gas containing organic silicon and a hazardous component and the exhaust of treated gas, in which the hazardous gas has been thermally decomposed in the combustion chamber, are switched in succession in each heat-storage chamber by operating the open/close valve. In this case, atmospheric temperature of the combustion chamber is maintained in the range of 750-810°C.



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